

# Readout of the LHCb pixel hybrid photon detectors

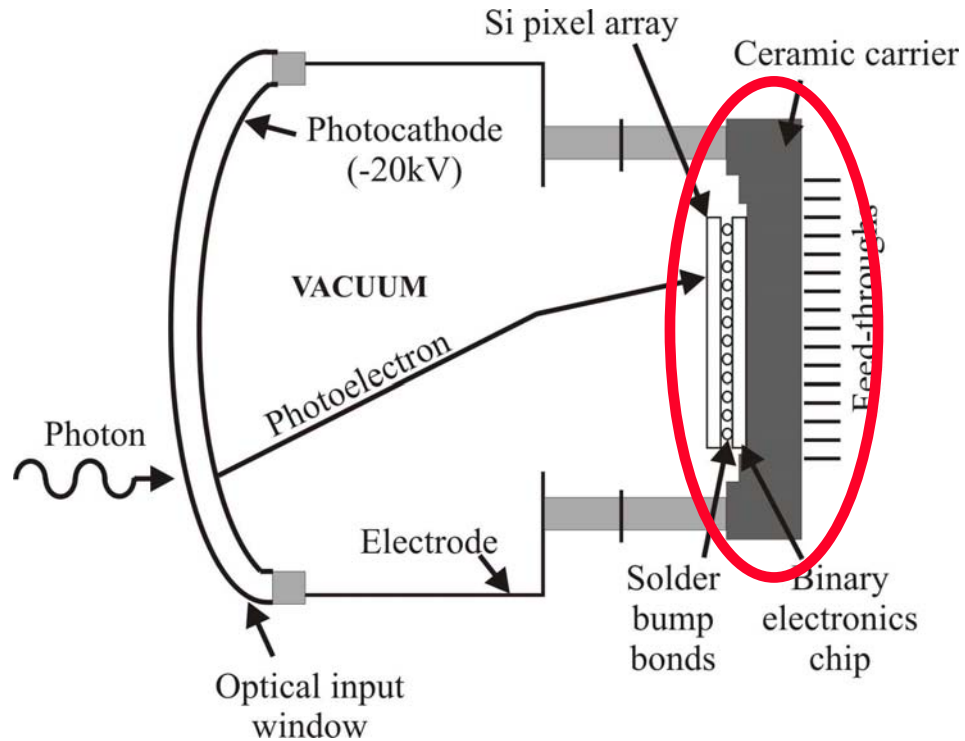
Ken Wyllie on behalf of the LHCb collaboration and industrial partners

- The pixel hybrid photon detector (HPD)
- Requirements for the electronics
- Design of the pixel chips
- Test results
- Design of the sensors
- Bump-bonding and packaging
- Conclusion

HPD details and tests presented by Laura Somerville earlier today



# The pixel hybrid photon detector



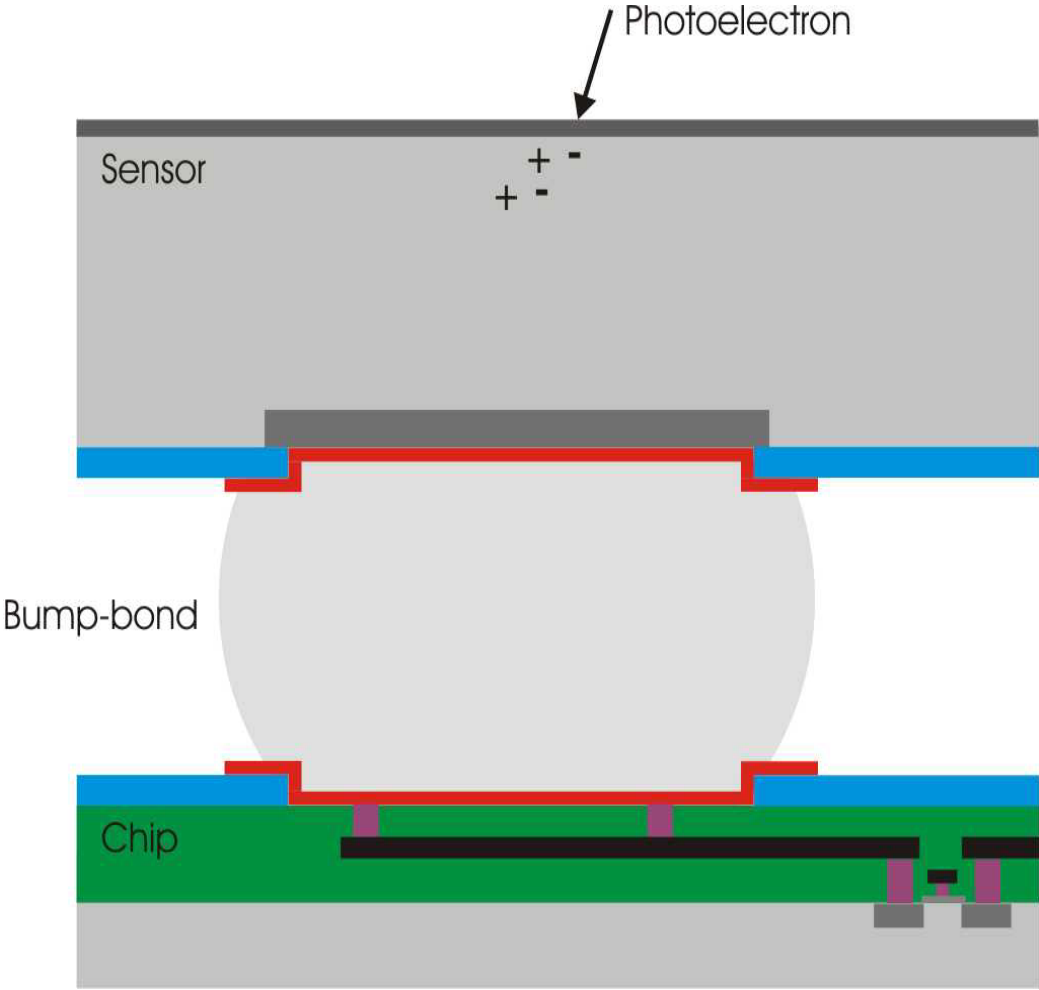
## Electronics inside HPD:

- Low noise (low capacitance)
- High channel density possible (data processing inside)

~ 500 HPDs will equip the LHCb RICH



# Hybrid pixel detector



# Requirements for the electronics

- Low noise – pattern recognition
- Low & uniform detection threshold  $\sim 2000e^-$  (signal  $\leq 5000$ )
- 25ns time precision (LHC)
- $500\mu\text{m} \times 500\mu\text{m}$  channel size (factor 5 demagnification)
- 16mm x 16mm active area
- 4% maximum time occupancy
- External trigger at  $\sim 1\text{MHz}$
- Compatible with HPD manufacturing

Design choices:

Physics performance not enhanced by resolving 1 or 2 or 3 photoelectrons

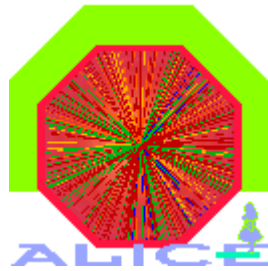
- ⇒ choice of binary architecture (0 or 1)
- ⇒ all digital I/Os – try to make it plug-and-play!



# Design of the pixel chip

History: Omega 1, 2, 3  
ALICE1test (use of radiation-tolerant layout)  
ALICE2test (0.25 $\mu$ m CMOS & radiation-tolerant layout)

ALICE1LHCB (2000): full scale pixel readout chip  
two applications, chip configured appropriately



ALICE happy



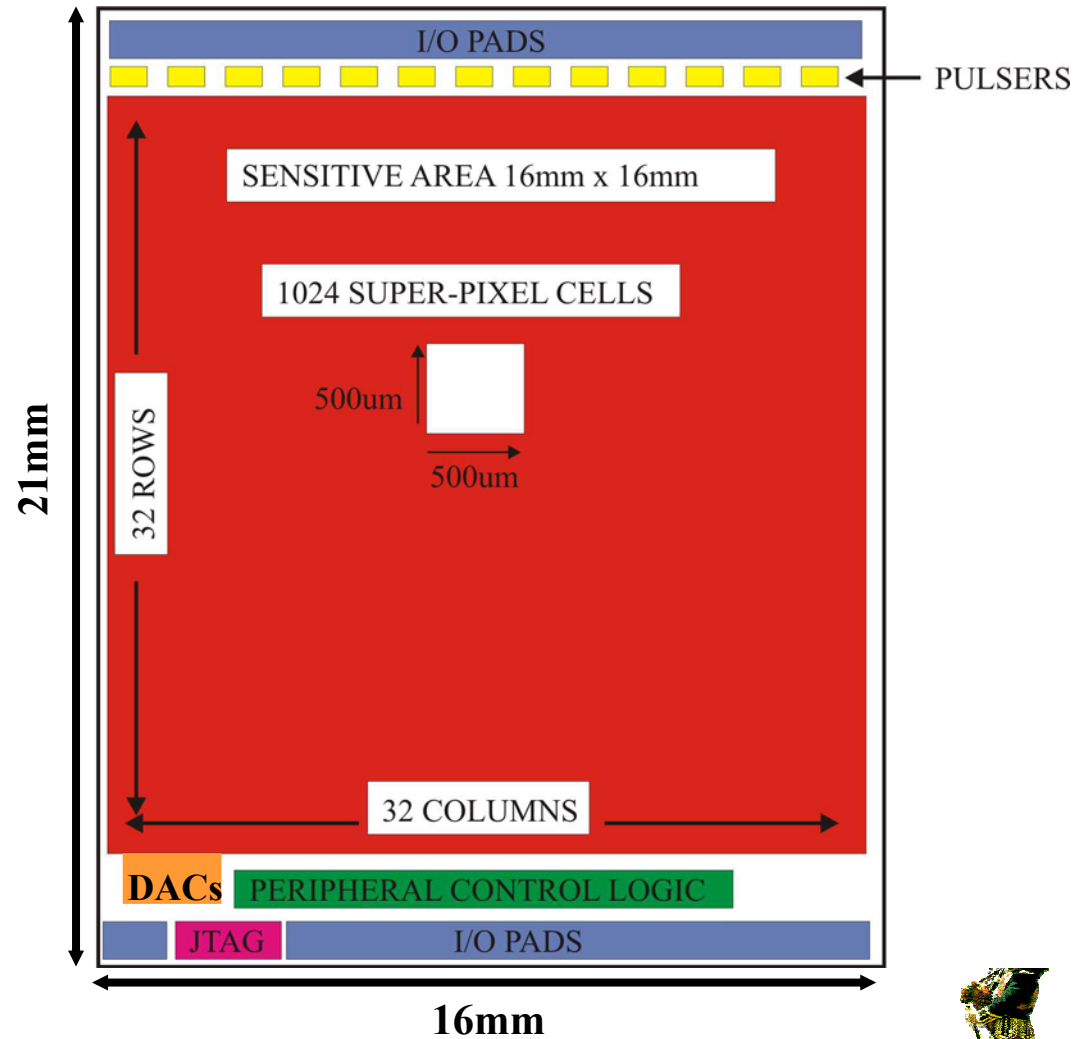
LHCb almost happy

LHCBPIX1 (2001): dedicated to LHCb

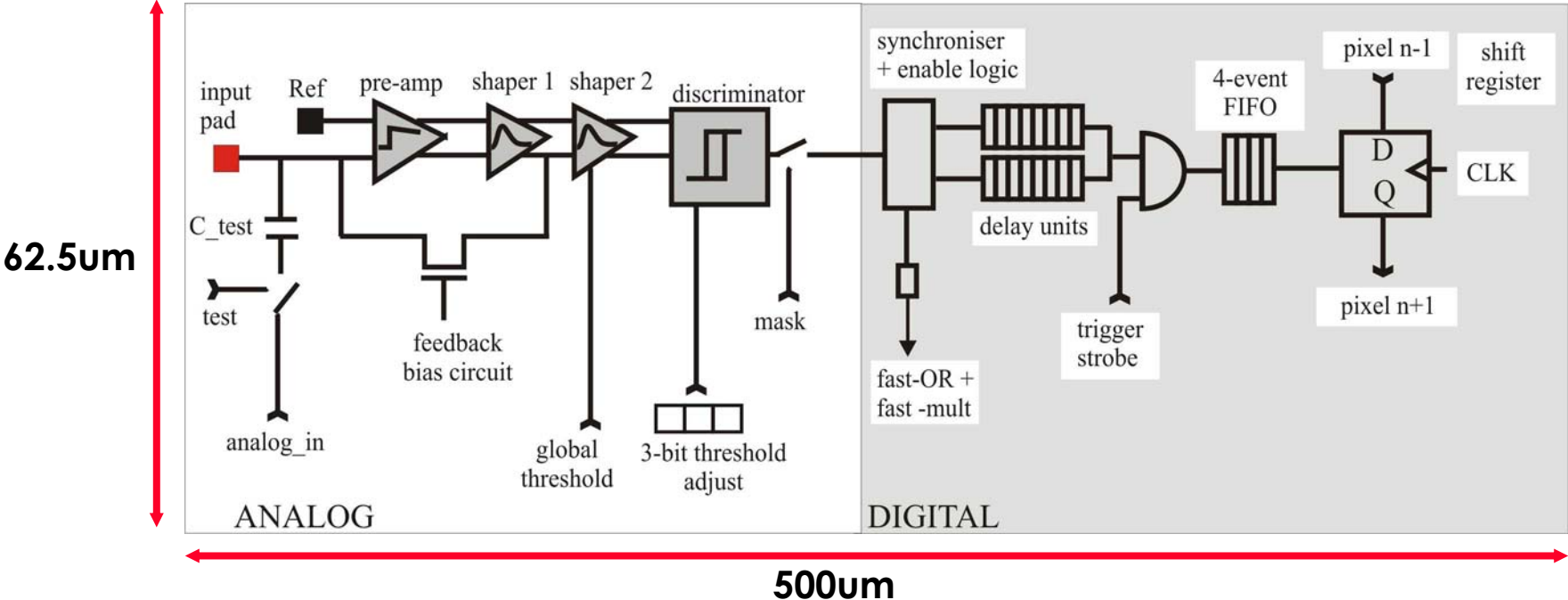


# LHCBPIX1 chip

- Commercial 0.25 $\mu$ m CMOS process
- 6 metal layers
- Radiation-tolerant layout
- 13 million transistors
- 1.8W total power (40MHz clk, 1MHz trig)
- Current-starved logic
- Internal DACs for biasing



# Pixel Cell Description



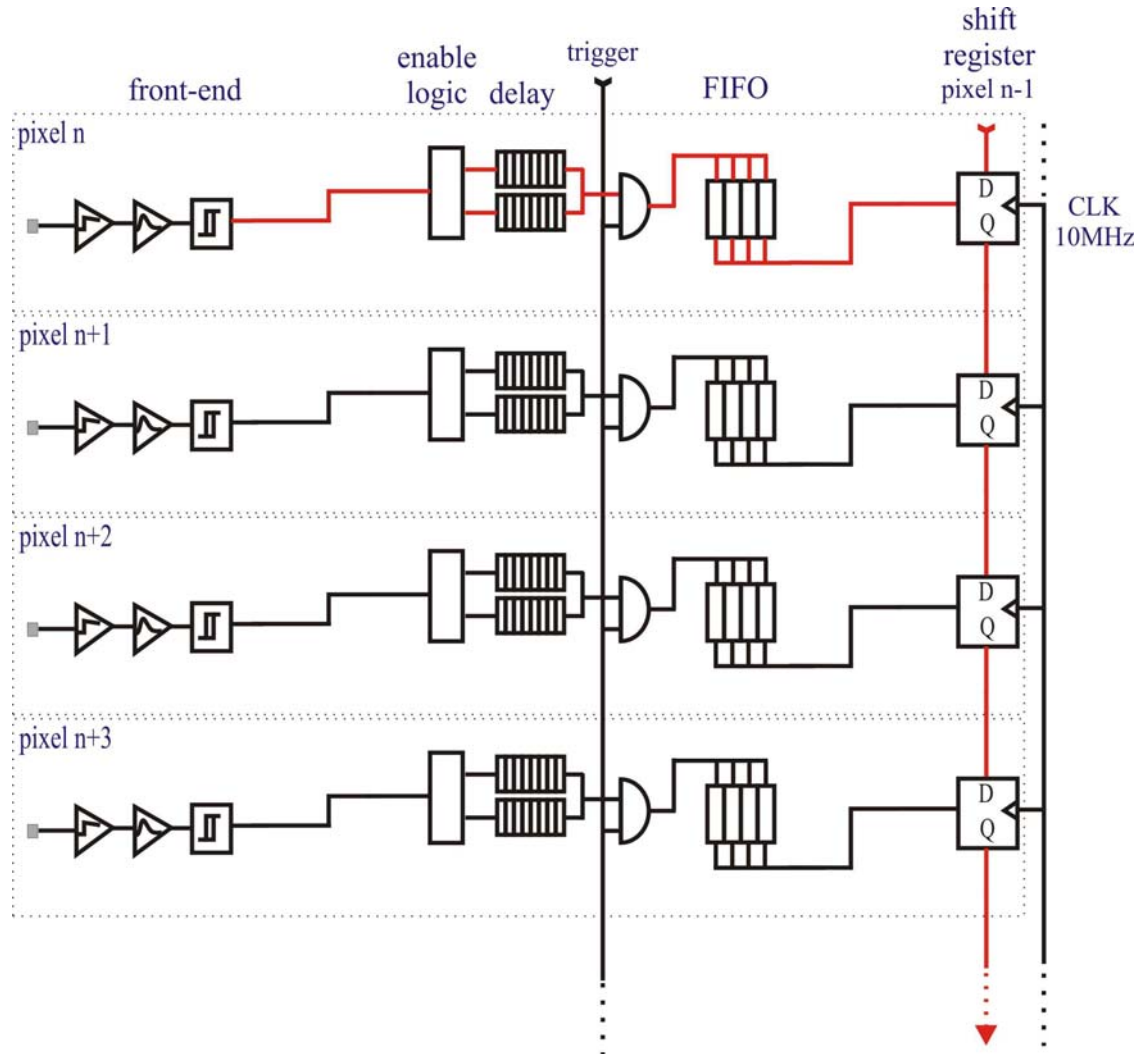
One super-pixel (500um x 500um) = 8 pixels (62.5um x 500um)

User can select:

1. ALICE mode = 8192 pixels
2. LHCb mode = 1024 super-pixels

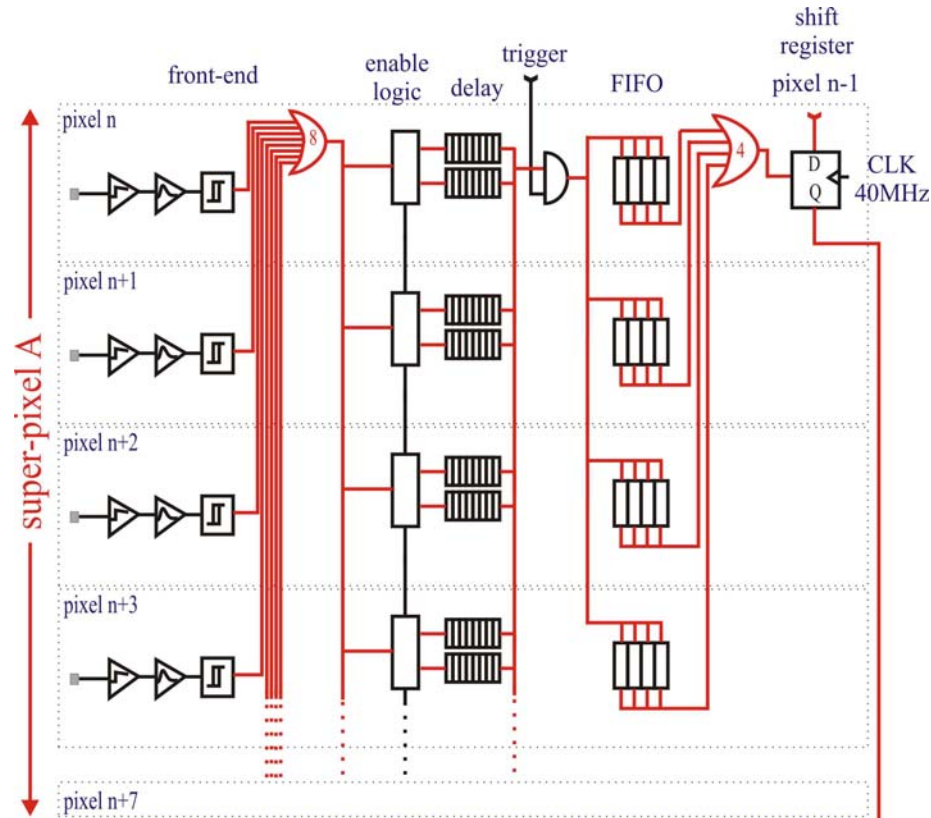


# ALICE mode





# LHCb mode



## Advantages:

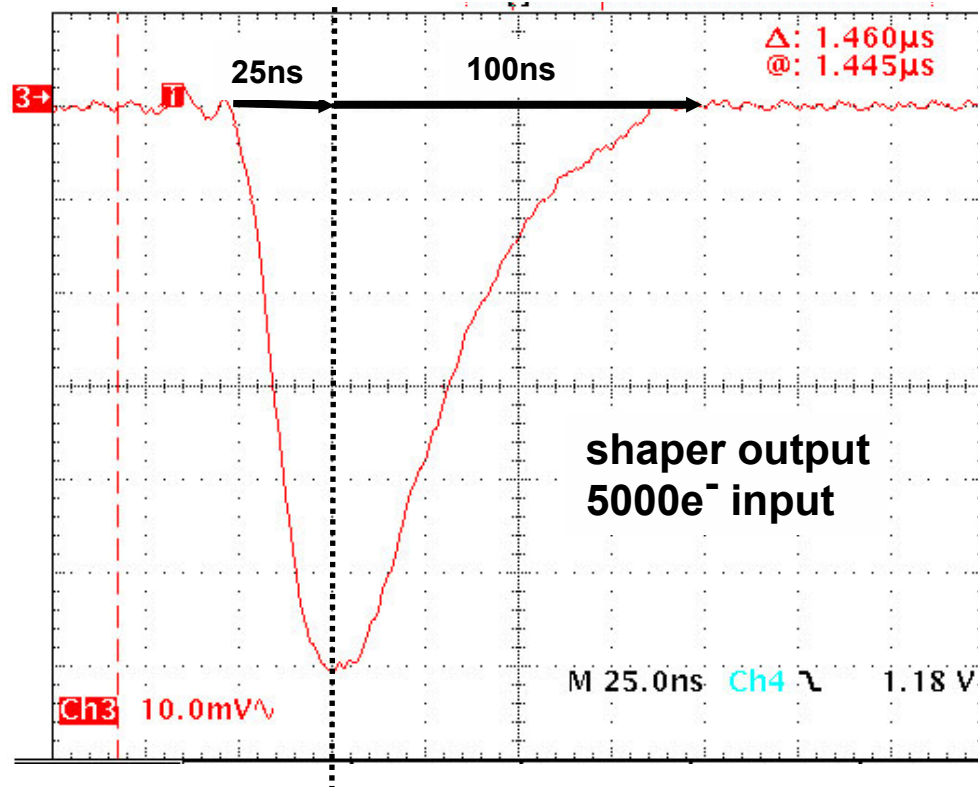
- Small input capacitance
- Front-end occupancy divided by 8



# Electrical Test Results (1)

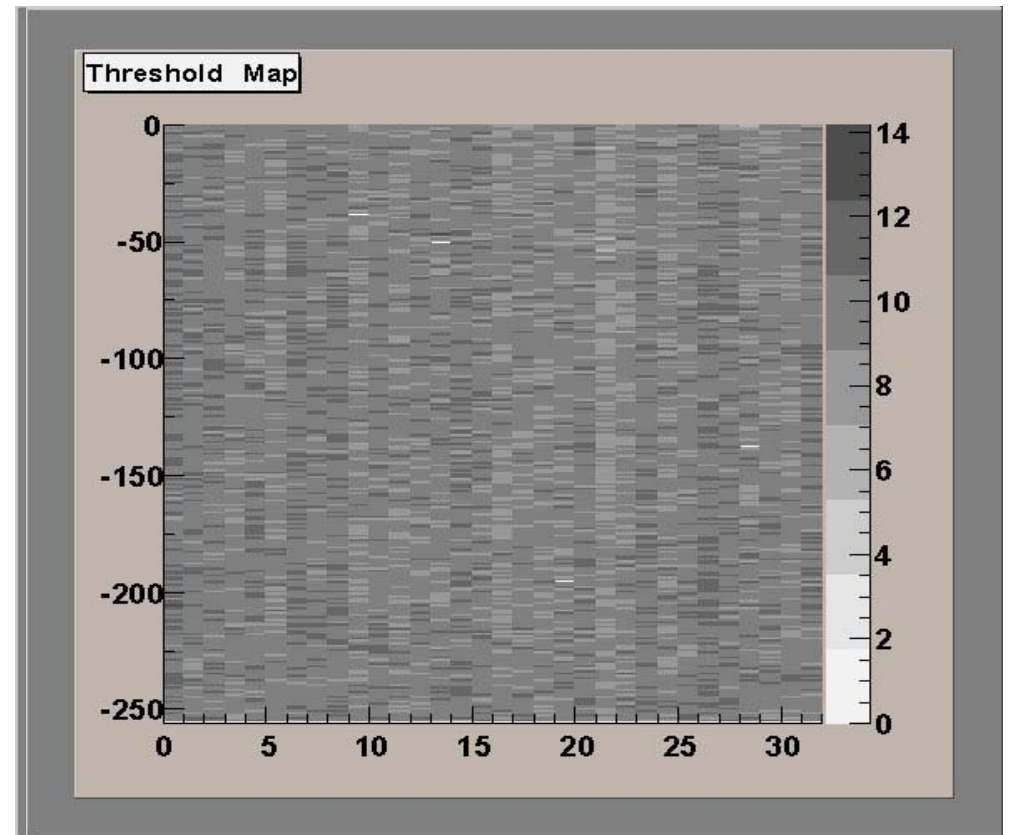
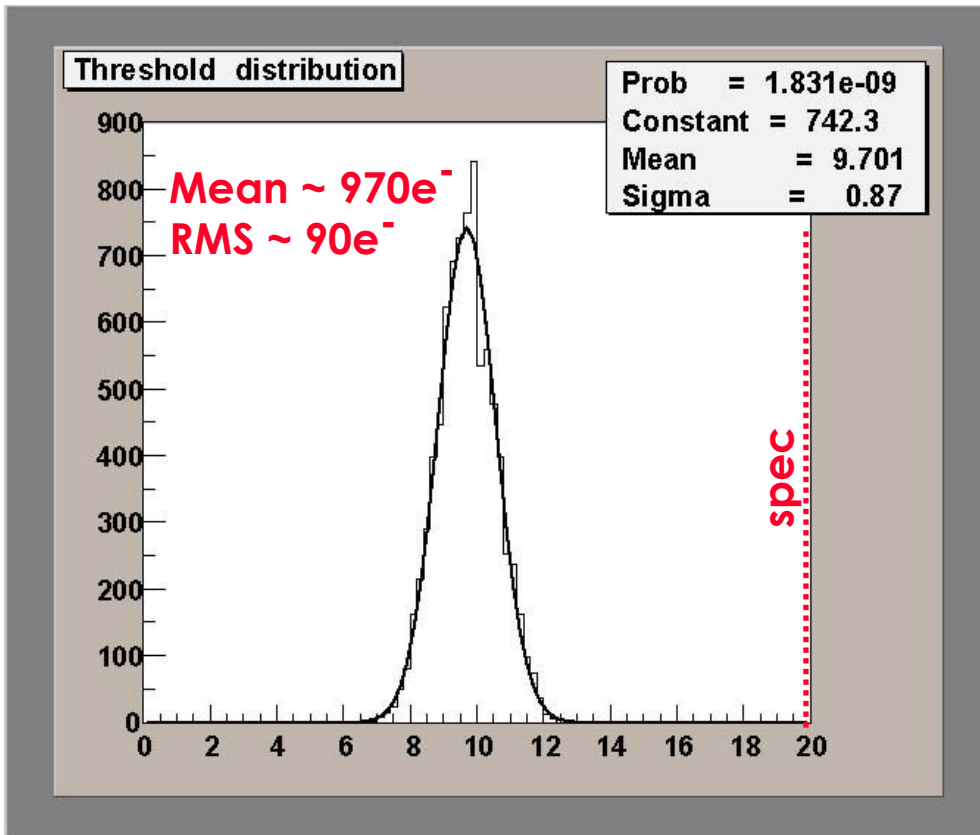
Using calibration pulse  
Analog front-end fast recovery – low risk of pile-up

Shaper output



# Electrical Test Results (2)

## Discriminator threshold & noise



(Without individual threshold adjustment)

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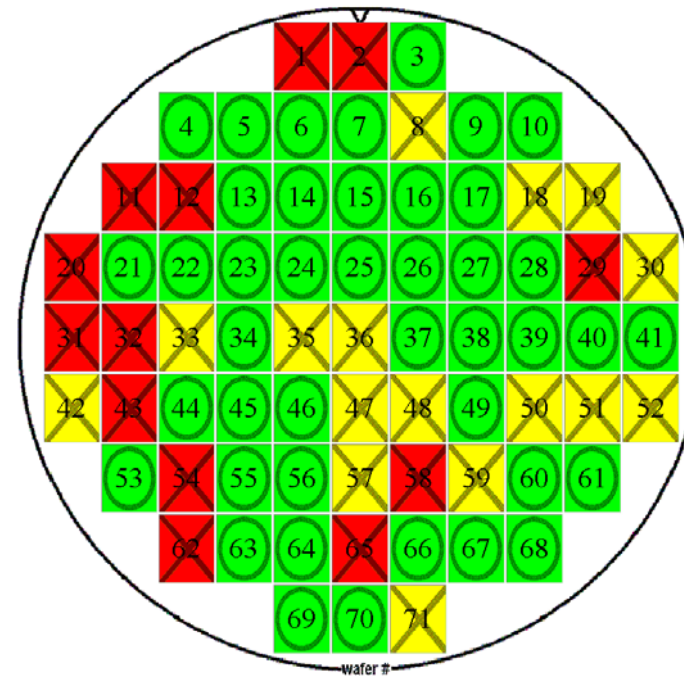


# Chip testing

Custom test system designed for probe testing of wafers (& bump-bonded assemblies, anodes, HPDs.....)

Known-good-die identified before bump-bonding

55% yield of good chips

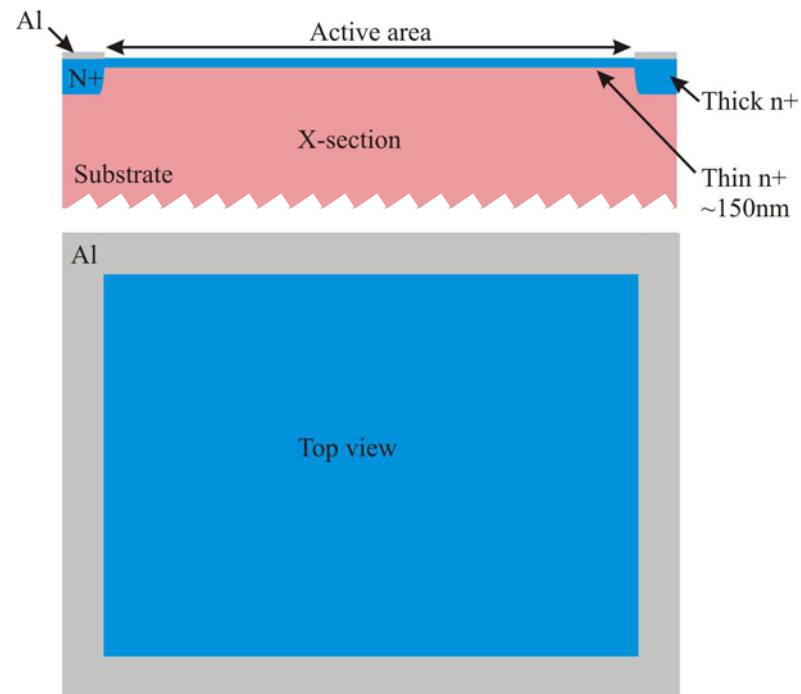


# Silicon Sensor

Optimised for photoelectron detection (Canberra, Belgium)

Minimise energy lost on ohmic side of detector

Diode side: simple p-on-n pixel diodes



Ohmic side

20keV electron penetrates  
~ 5 $\mu$ m depth of Si



# Bump-bonding (1)

Two 'standard' methods of fine-pitch bump-bonding (in High Energy Physics)

- Indium bumps – compression or reflow, melting point 156°C
- Solder bumps – reflow, eutectic (SnPb 60/40) melting point 183°C

Problems with both because of:

1. high T curing of glue (non-outgassing) used for packaging at 400°C
2. high temp processing of HPD at 300°C (bake-out to remove contaminants)

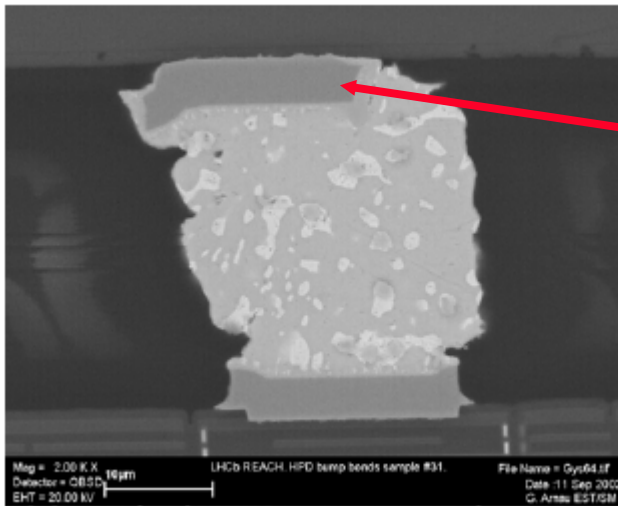
Eutectic bumps melt:

- Connections suffer during thermal expansion/contraction
- Dissolution of under-bump-metals into molten solder



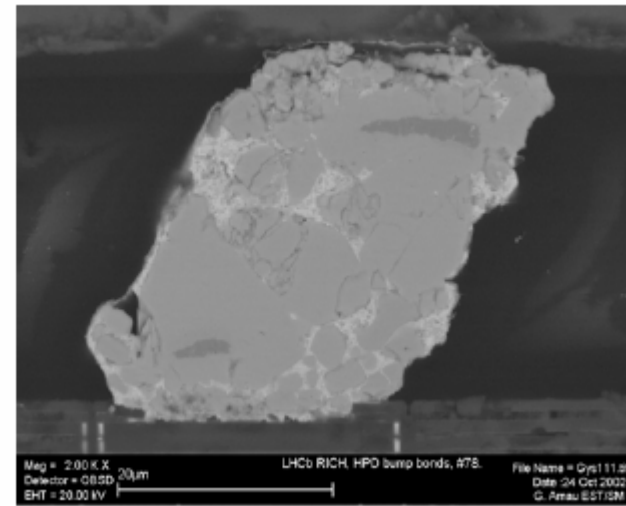
**Eutectic before bake**

**Sensor**



**Under  
Bump  
Metal  
(UBM)**

**Eutectic after bake**

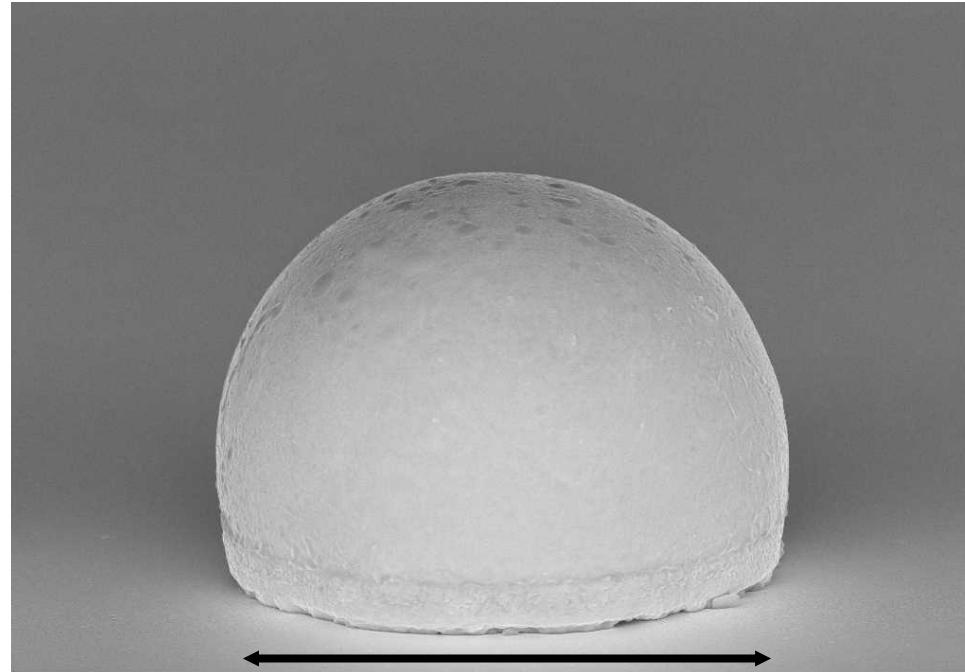


**Chip**



## Bump-bonding (2)

VTT, Finland: bump-bonding recipe using solder with high melting-point (SnPb 10/90)



25um

Long programme of tests (bake-outs, SEM photos, pull-strength tests, prototype HPDs) has successfully proven the bump reliability

VTT producing assemblies with > 99% good bumps

K.Wyllie, CERN

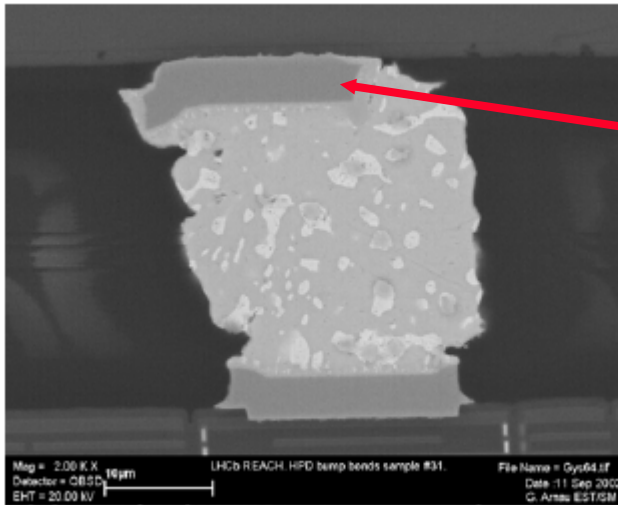
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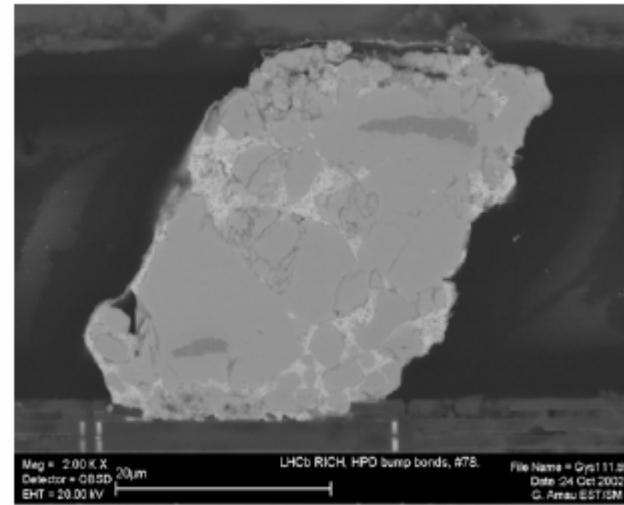
**Eutectic before bake**

**Sensor**



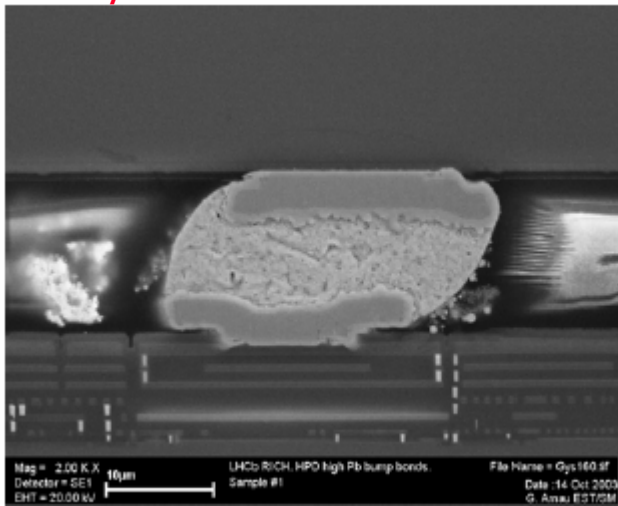
**Under  
Bump  
Metal  
(UBM)**

**Eutectic after bake**

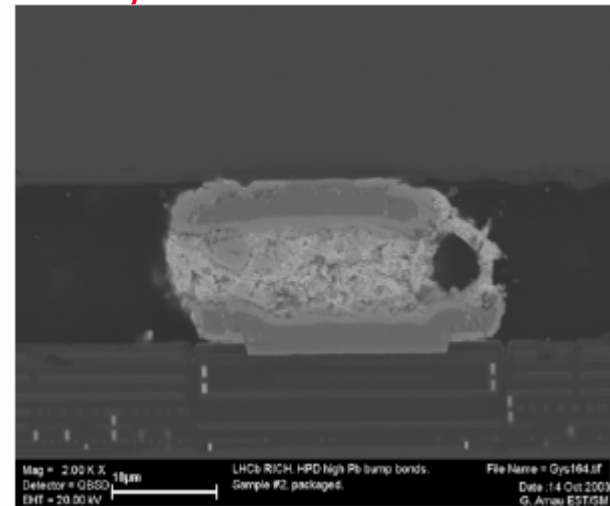


**Chip**

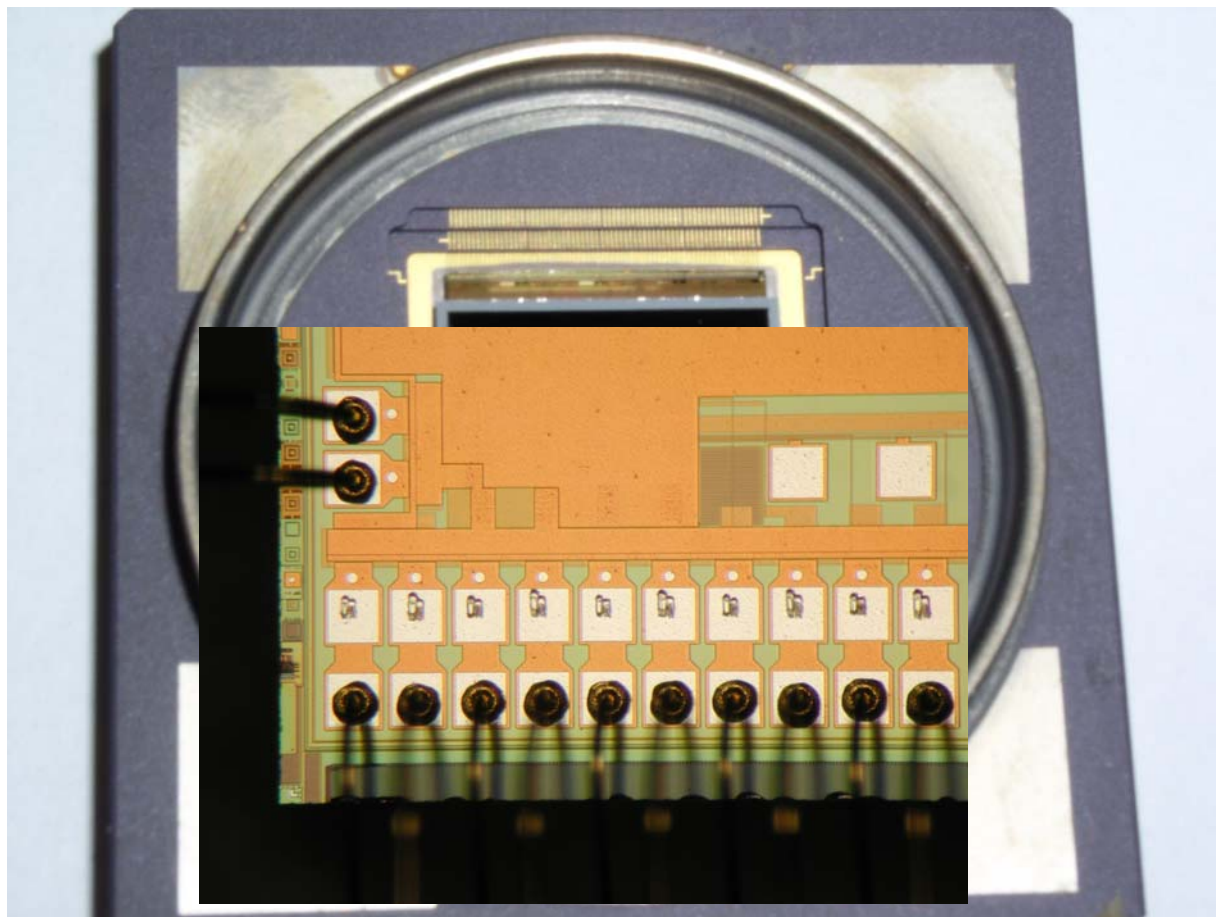
**10/90 SnPb before bake**



**10/90 SnPb after bake**



# Packaging



**Ceramic carrier produced by Kyocera, Japan  
- Good thermal conduction**

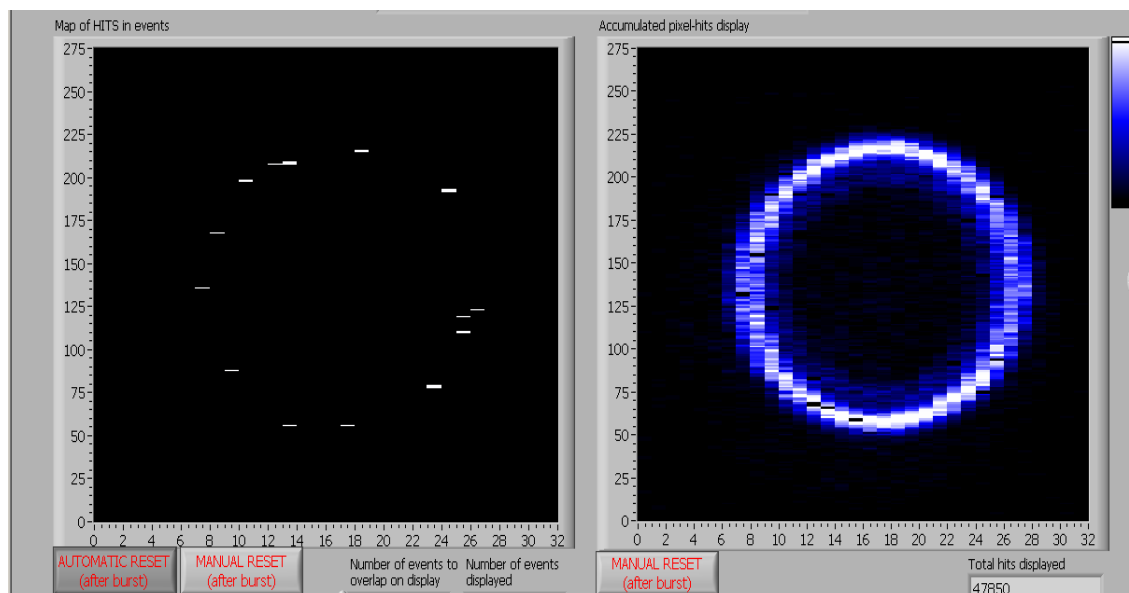


## ..... and finally the HPD

Since solving bump-bonding challenge, 6 prototype HPDs produced by DEP, Holland

All tested in lab with excellent efficiency & low noise (dominated by dark counts from photocathode)

Testbeam results – clean Cherenkov rings (see Laura's talk)



# Conclusion

- Silicon pixel sensor & electronics chip designed for HPD application
- Electrical requirements of chip fulfilled
- New bump-bonding process developed & verified
- Prototype HPDs produced & meet requirements
- The long production process is underway.....



K.Wyllie, CERN

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◆ **Spare slides**



**K.Wyllie, CERN**



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# Production

Production is underway – final goal = 500 HPDs for LHCb

Challenge of logistics: we have 6 industrial collaborators in Japan, Belgium, France, Finland & Holland

Many testing stages:

- 1) Identify Known-Good-Die of pixel chip
- 2) Test bump-bonded assemblies
- 3) Test packaged assemblies (anode)
- 4) Test HPDs

Stages 1) – 3) at CERN, 4) in collaborating institutes

Intermediate verification steps by companies => yield factor at every step

Custom test system produced for institutes & companies



# Silicon Sensor

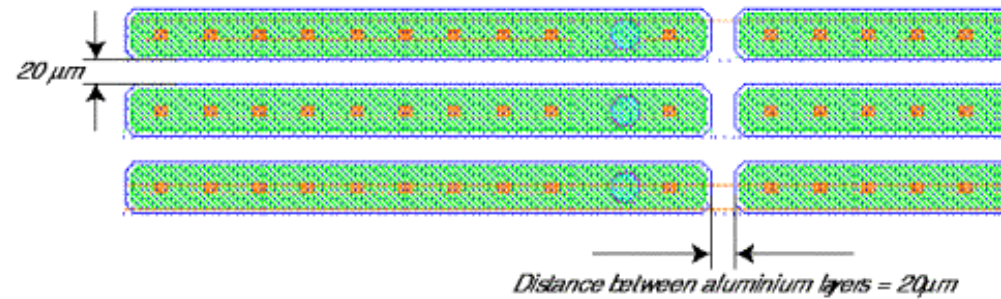
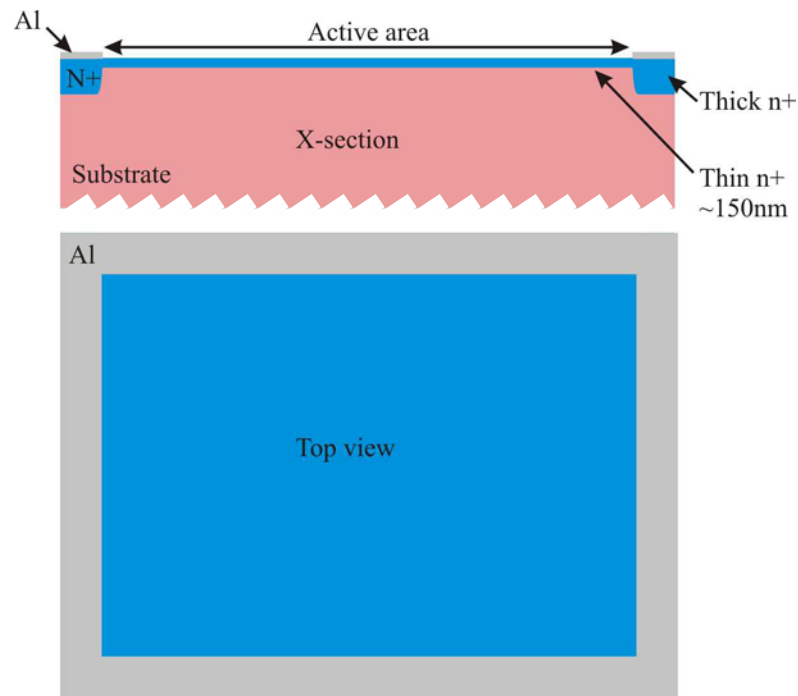
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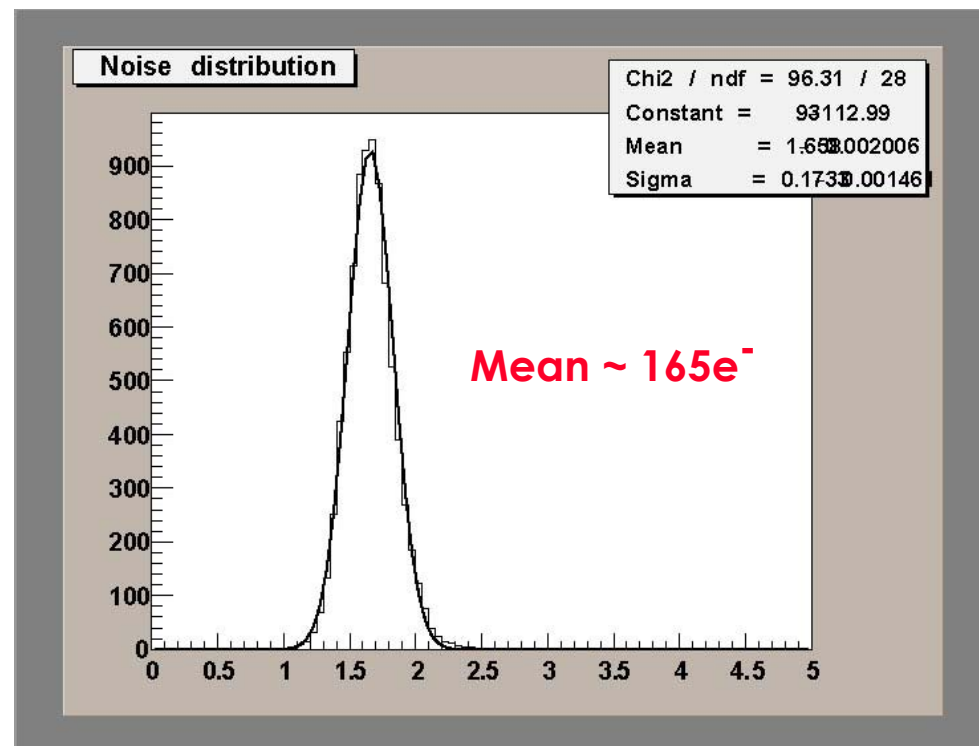
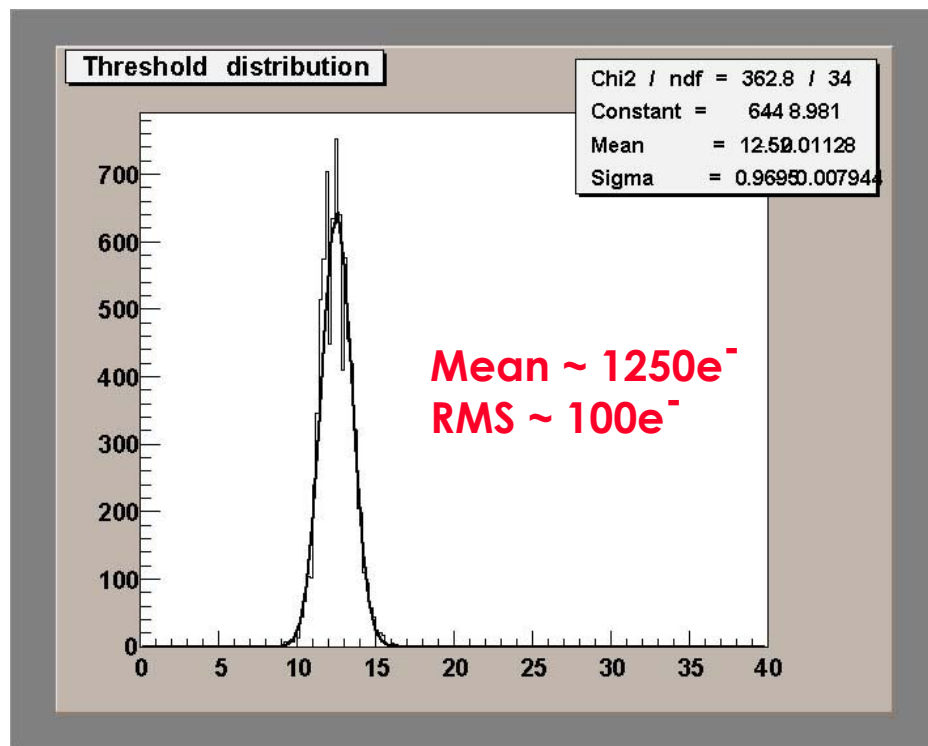
Diode side: simple p-on-n pixel diodes

Ohmic side:

Diode side: simple p-on-n pixel diodes

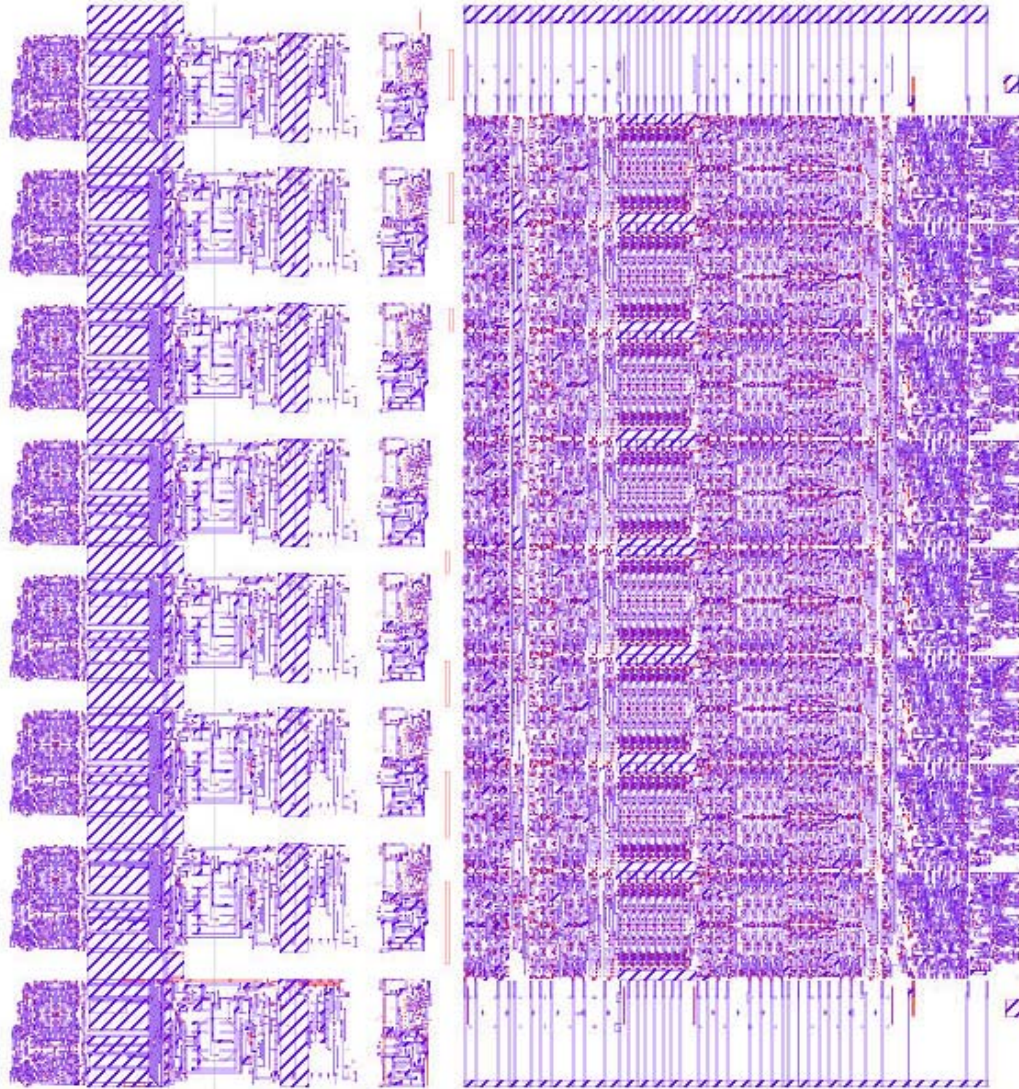


# Electrical Test Results - assembly





# Super-pixel layout



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